**Please insert the following heading on page 1, between line 1 and line 2:**

--Field of the Invention--

**Please insert the following heading at page 1, between line 3 and line 4:**

--Background Information--

**Please replace the paragraph beginning at page 5, line 1, with the following paragraph:**

--The network system of the present invention is equipped with the first LAN, the second LAN, and control or separation means and memory means connected between the first and second LANs. The separation means separates the first and the second LAN so that they do not influence each other and controls accessibility to the memory means from the both first and second LANs.--

**Please replace the heading beginning at page 6, line 5, with the following heading:**

--DETAILED DESCRIPTION OF THE PREFERRED EMBODIMENTS--

**Please replace the paragraph beginning at page 6, line 10, with the following paragraph:**

--In Fig. 1, a device-side LAN 101 as a second LAN comprising a focused ion beam apparatus is installed in the measurement room located separately from the factory and is connected to a factory-side LAN 109 as a first LAN via TCP/IP through a control means 110 (hereinafter referred to as "separating means") which separates the device-side LAN 101 and the factory-side LAN 109 so that the two LANs do not influence each other. The factory-side LAN 109 is not described in detail but connects, for example, computers via bus lines. The device-side LAN 101 is equipped with a host computer 102 for input instructions for processing such as observing and working of the workpiece, analysis of collected data, or display of workpiece images. In addition, as processing elements, this LAN 101 as an optical system controller 103 for controlling focusing and magnification by controlling a condenser lens, a beam blanking electrode, or a scanning electrode to control an ion beam with an electric field, an optical axis controller 104 for axially aligning an ion source mounted on an ion source stage by using an actuator and piezoelectric element, a vacuum evacuation unit 105 for evacuating the workpiece room where the workpiece is mounted,